

Electronic Supplementary Information (ESI) for Nanoscale.

**Rapid fabrication of solid-state nanopore with high  
reproducibility using helium ion microscope over a large area**

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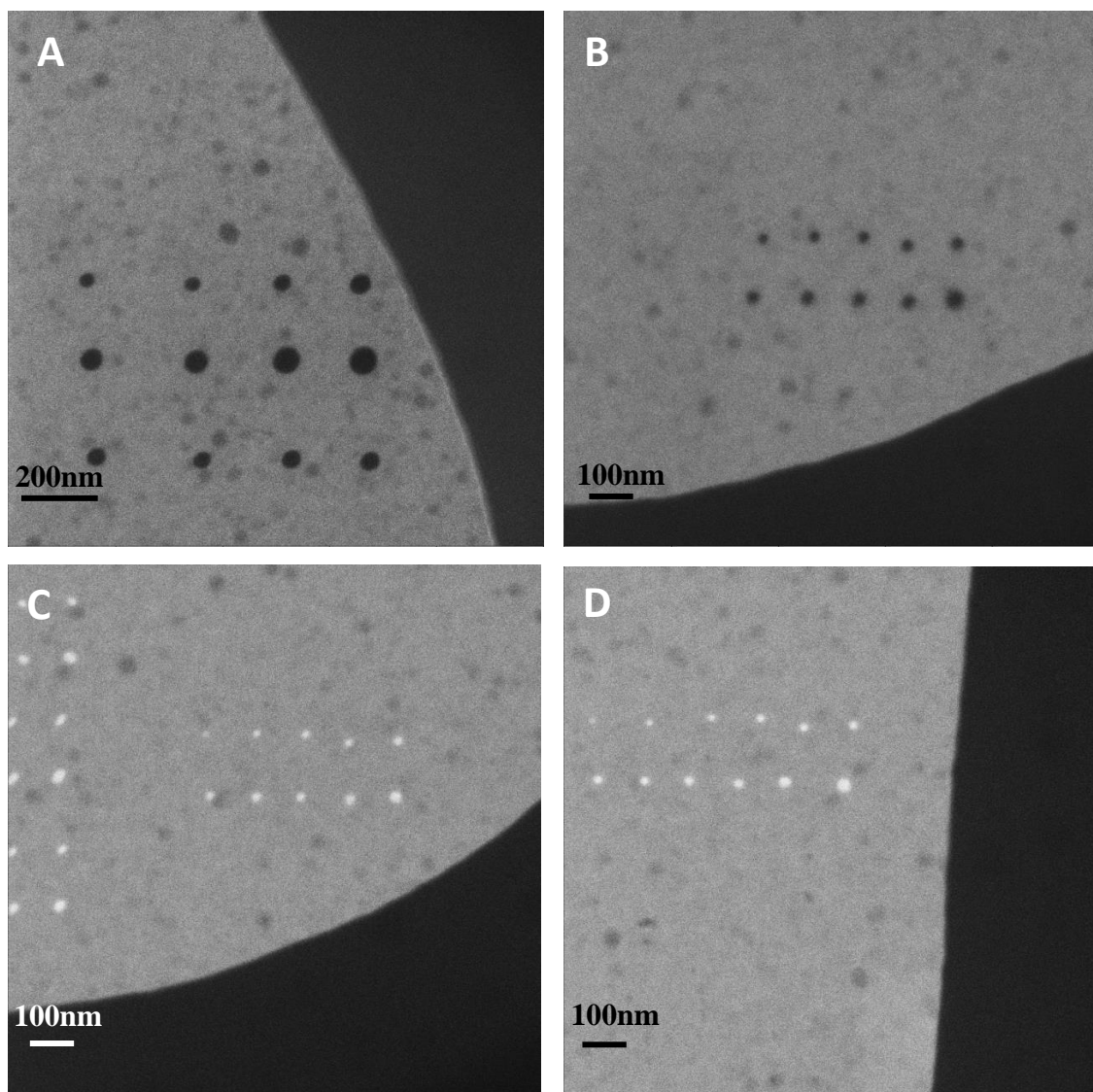


Figure S1. HIM images to test the nanopore exposure time series: (A)-(B) dirty samples; (C)-(D) clean samples after oxygen plasma cleaning.

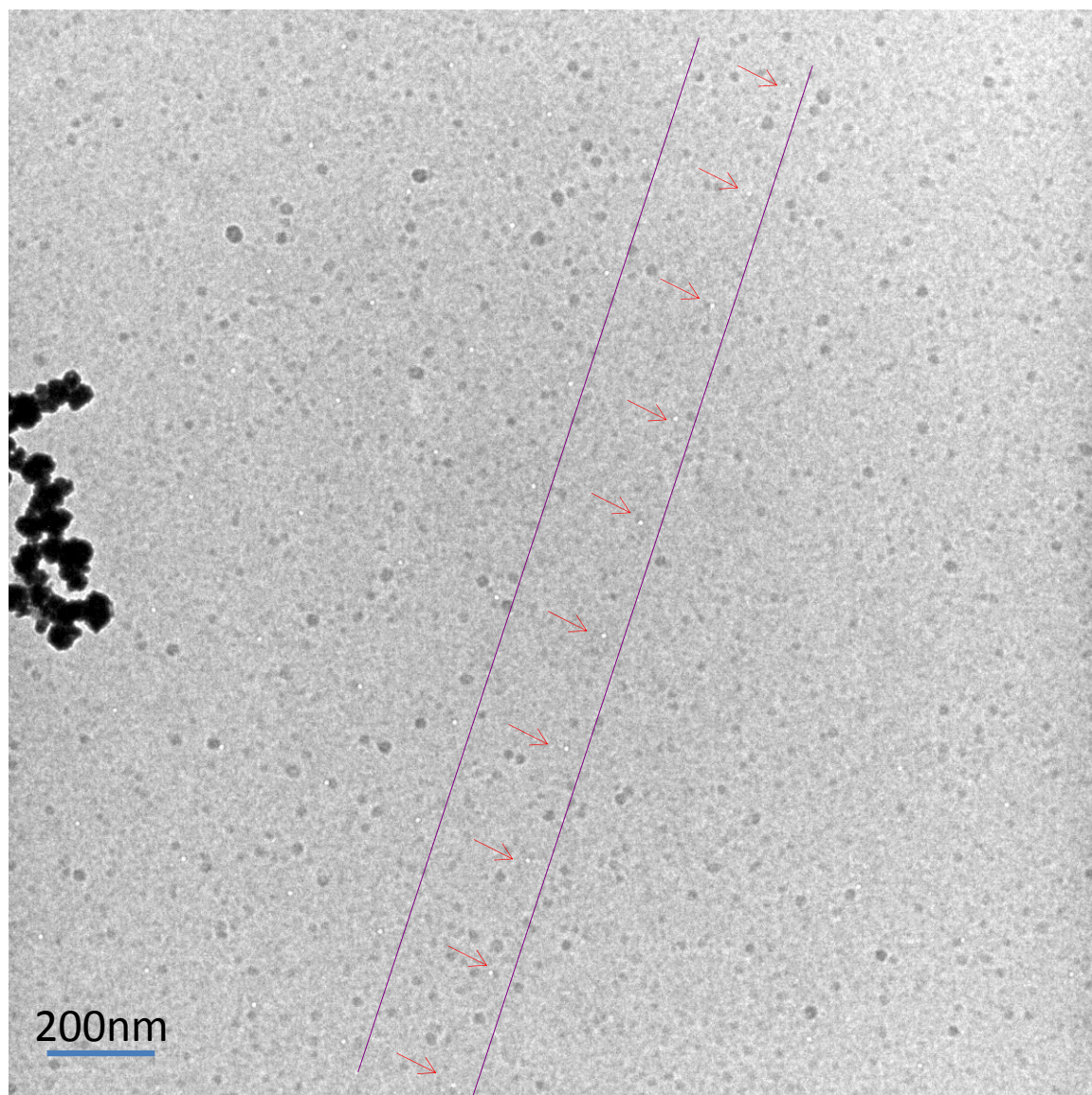


Figure S2. TEM images of overall view of 10×5 array: purple lines meaning x-direction and red arrows meaning nanopore locations.



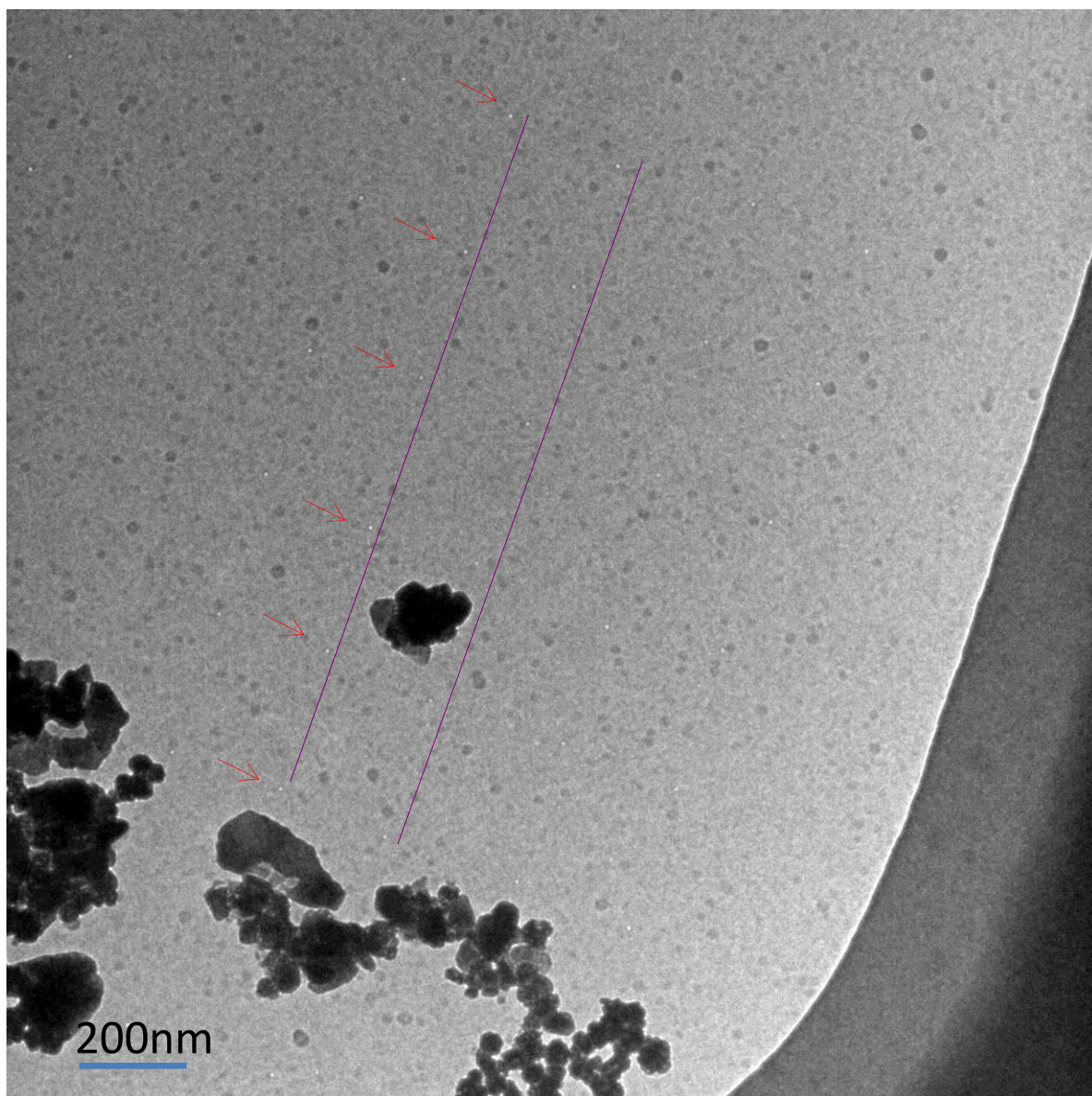


Figure S3. TEM images of overall view of 6×5 array: purple lines meaning x-direction and red arrows meaning nanopore location.

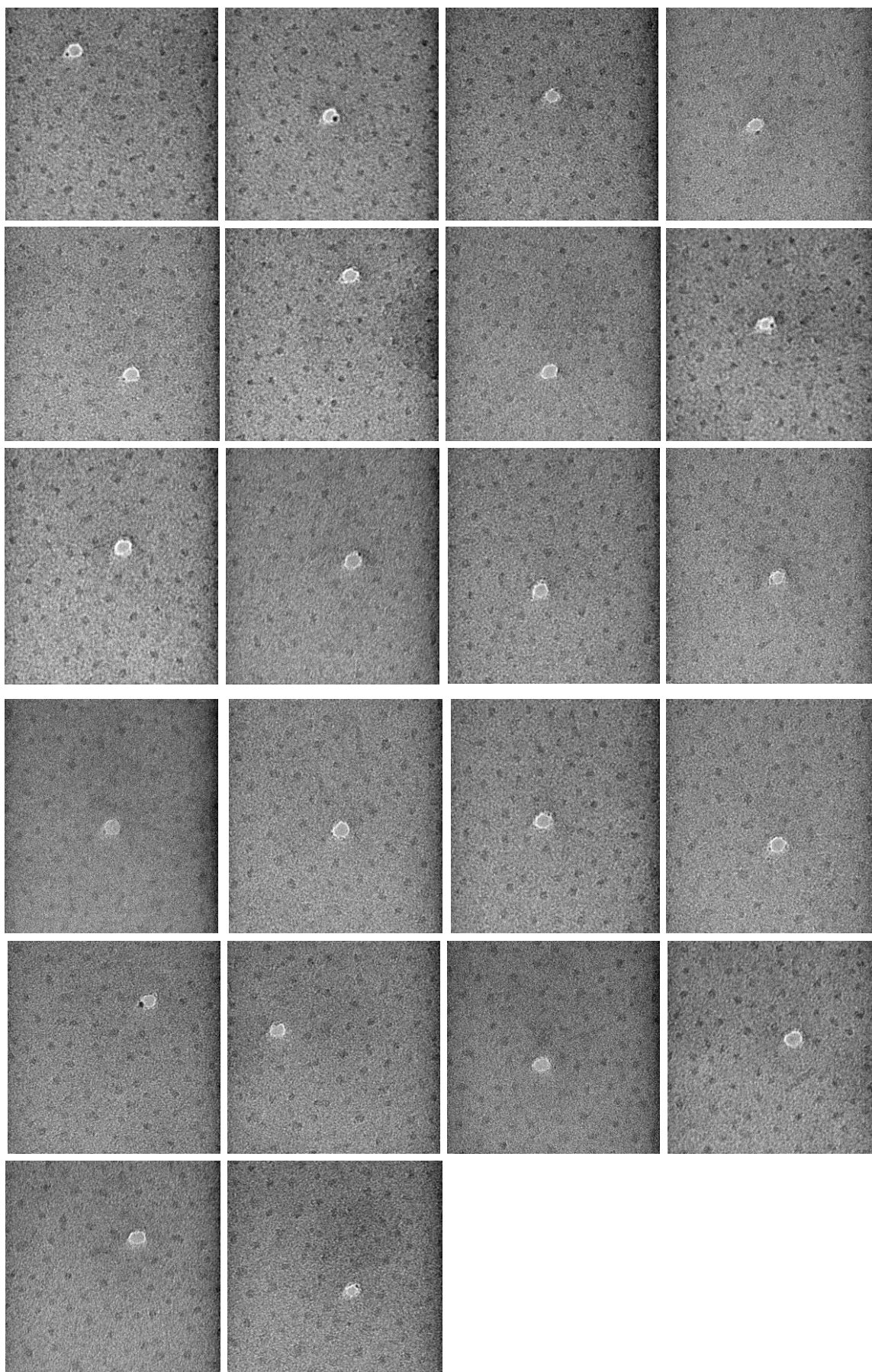


Figure S4. TEM images of 22 individual nanopores in  $6 \times 5$  arrays with exposure time 0.3s. The field of view of image is 90nm.

Table S1. Nanopore dimensions (long axis  $\times$  short axis, nm) from TEM images for exposure time 0.3s

1	2	3	4	5	6	7	8	9	10	11
5.4 $\times$ 5.0	5.9 $\times$ 4.7	5.0 $\times$ 4.9	5.9 $\times$ 4.7	6.5 $\times$ 5.9	5.7 $\times$ 5.4	7.0 $\times$ 5.7	7.1 $\times$ 6.3	7.1 $\times$ 5.0	6.7 $\times$ 5.9	6.2 $\times$ 5.8
12	13	14	15	16	17	18	19	20	21	22
6.7 $\times$ 5.0	6.1 $\times$ 5.8	6.1 $\times$ 5.3	6.0 $\times$ 5.5	6.0 $\times$ 5.5	7.0 $\times$ 5.8	6.2 $\times$ 6.2	6.2 $\times$ 6.1	7.0 $\times$ 5.5	6.6 $\times$ 5.4	6.2 $\times$ 5.2

Table S2. Nanopore dimensions (long axis  $\times$  short axis, nm) from TEM images for exposure time 0.5s.

1	2	3	4	5	6	7	8	9	10
7.8 $\times$ 6.7	8.9 $\times$ 6.7	8.8 $\times$ 6.7	8.0 $\times$ 6.4	8.3 $\times$ 6.6	9.5 $\times$ 6.9	8.8 $\times$ 7.2	7.8 $\times$ 7.0	8.0 $\times$ 6.5	9.3 $\times$ 7.0
11	12	13	14	15	16	17	18	19	20
9.5 $\times$ 8.2	9.5 $\times$ 7.2	8.7 $\times$ 7.2	8.5 $\times$ 8.0	8.3 $\times$ 7.7	9.7 $\times$ 6.5	9.6 $\times$ 7.0	9.1 $\times$ 6.5	8.0 $\times$ 7.0	8.4 $\times$ 7.8
21	22	23	24	25	26	27	28	29	30
9.2 $\times$ 7.7	9.7 $\times$ 8.4	8.4 $\times$ 8.1	8.2 $\times$ 7.8	7.9 $\times$ 7.5	7.6 $\times$ 7.2	10.3 $\times$ 7.2	10.5 $\times$ 6.8	9.6 $\times$ 7.1	10.0 $\times$ 6.7

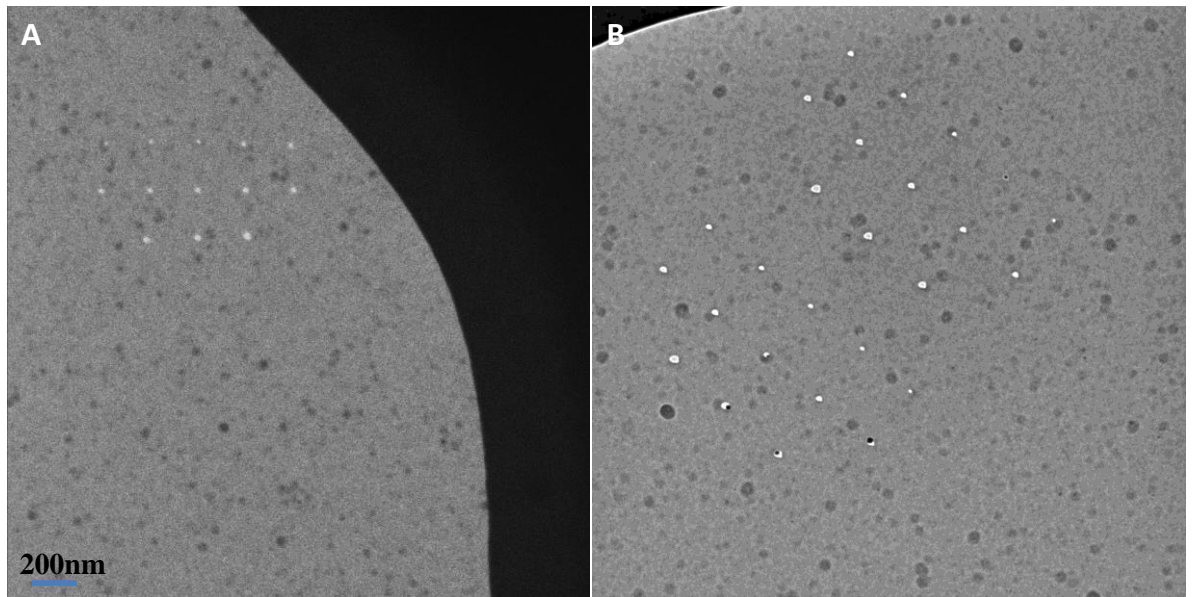


Figure S5. Images for nanopore arrays with exposure time series (A) quick HIM images after 1<sup>st</sup> milling of the array ; (B) TEM images for two arrays.



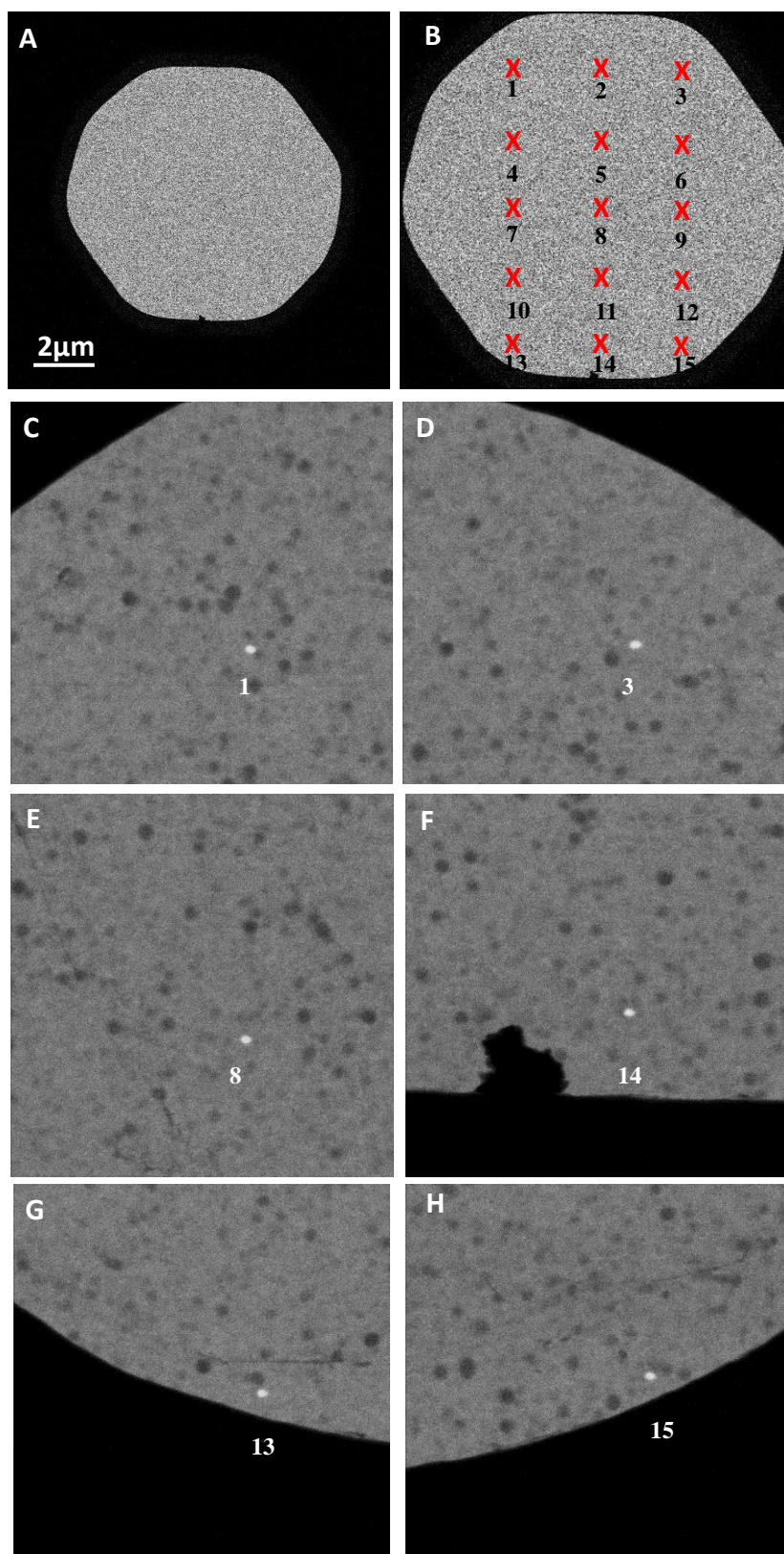


Figure S6. HIM images for 3×5 arrays with automated milling and imaging mode using exposure time 10s: (A) overall disc view; (B) positions of 3×5 arrays; (C) nanopore on position #1; (D) nanopore on position #3; (E) nanopore on position #8; (F) nanopore on position #14; (G) nanopore on position #13; (H) nanopore on position #15. The field of view for (C)-(H) is 2μm.